

Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

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4-8-06*
1. (Currently Amended) A lithocell comprising:
 - a lithographic apparatus, comprising:
 - an illuminator configured to condition provide a beam of radiation,
 - a support structure configured to hold a patterning device, the patterning device configured to impart the beam with a pattern in its cross-section,
 - a substrate table configured to hold a substrate, and
 - a projection system configured to project the patterned beam onto a target portion of the substrate;
 - a track comprising one or more processing devices; and
 - a transport system, outside of the lithographic apparatus and the track, configured to transport the substrate along an elongate transporter pathway between the track and the lithographic apparatus, wherein the track and the lithographic apparatus are side by side along their respective long sides and the transport system extends along a short side of the lithographic apparatus, or the track, or both the lithographic apparatus and the track.
 2. (Original) A lithocell according to claim 1, wherein the transport system comprises its own mini-environment.
 3. (Currently Amended) A lithocell according to claim 1, wherein the track and the lithographic apparatus are placed side-by-side and the transport system comprises a linear transporter pathway between the track and the lithographic apparatus them.
 4. (Original) A lithocell according to claim 1, wherein the transport system comprises at least two transporter pathways, one configured to transport the substrate from the track to the lithographic apparatus and one configured to transport the substrate from the lithographic apparatus to the track.